

	Application No.	Applicant(s)
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Notice of Allewshilling	10/653,225	YU ET AL.
Notice of Allowability	Examiner	Art Unit
·	DiLinh Nguyen	2814
The MAILING DATE of this communication appears on the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.		
1. This communication is responsive to 6/22/05.		
2. The allowed claim(s) is/are <u>1-16</u> .		
3. ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a) ☐ All b) ☐ Some* c) ☐ None of the:		
1. Certified copies of the priority documents have been received.		
2. Certified copies of the priority documents have been received in Application No		
3. Copies of the certified copies of the priority documents have been received in this national stage application from the		
International Bureau (PCT Rule 17.2(a)).		
* Certified copies not received:		
Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application. THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.		
4. A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.		
5. CORRECTED DRAWINGS (as "replacement sheets") must be submitted.		
(a) ☐ including changes required by the Notice of Draftsperson's Patent Drawing Review (PTO-948) attached		
1) hereto or 2) to Paper No./Mail Date		
(b) including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date		
Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d).		
6. DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.		
Attachment(s)		
1. Notice of References Cited (PTO-892)	5. 🔲 Notice of Informal F	Patent Application (PTO-152)
2. Notice of Draftperson's Patent Drawing Review (PTO-948)	6. ☐ Interview Summary Paper No./Mail Da	
3. ☑ Information Disclosure Statements (PTO-1449 or PTO/SB/0 Paper No./Mail Date 9/3/03	Paper No./Mail Da 08), 7. ⊠ Examiner's Amendr	ment/Comment
Examiner's Comment Regarding Requirement for Deposit of Biological Material	8. 🛛 Examiner's Stateme	ent of Reasons for Allowance
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		HOAV PHAM PRIMARY EXAMINER

U.S. Patent and Trademark Office PTOL-37 (Rev. 7-05) Art Unit: 2814

DETAILED ACTION

EXAMINER'S AMENDMENT

An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Mr. John E. Harrity on 8/31/05.

The application has been amended as follows:

In the claims:

Line 15, claim 1, delete "three gates" and insert, --tri-gate semiconductor device. —

Line 19, claim 12, delete "three gate electrodes" and insert, --tri-gate electrodes semiconductor device. –

Cancel non-elected claims 17-20.

REASONS FOR ALLOWANCE

Claims 1-16 are allowed.

The following is an examiner's statement of reasons for allowance:

The prior art of record fail to disclose the combination of all the process steps of forming a tri-gate semiconductor device recited in the base claims 1 and 12, including the combination of the process steps comprising depositing a metal layer on at least an upper surface of each of the amorphous silicon spacers being disposed on opposite

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sides of the structure; annealing the metal layer to convert the amorphous silicon spacers to crystalline silicon fin structures; removing a portion of the second dielectric layer and etching the gate material to form tri-gate semiconductor device (claim 1) and depositing a metal layer on at least an upper surface of each of the amorphous silicon structures being disposed on opposite sides of the structure; performing a metal-induced crystallization operation to convert the amorphous silicon structure to crystalline silicon structures; removing a portion of the second silicon oxide layer and patterning and etching the gate material to form tri-gate electrodes semiconductor device (claim 12).

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to DiLinh Nguyen whose telephone number is (571) 272-1712. The examiner can normally be reached on 8:00AM - 6:00PM (M-F).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Wael Fahmy can be reached on (571) 272-1705. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

DLN

PRIMARY EXAMINER

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